

Strongly strained VO₂ thin film growth

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Vanadium dioxide has a temperature-driven metal-semiconductor transition at 68 °C (bulk). There has been a lot of interest in the workings of this transition, which has been explained as either a Mott- or Peierls-transition or a collaborative effect of both. [1] The role of the lattice in the transition is exploitable by strain-engineering VO₂, e.g. using epitaxial strain in thin film growth, to increase or decrease the transition temperature and thus facilitate applications in technology.

We grow VO₂ on RuO₂ with the rutile *c* axis in-plane by means of reactive MBE and using atomic oxygen from a thermal cracker. Because of the very large lattice mismatch of 8.1 %, a large tensile strain is expected that would increase the transition temperature beyond the previously reported range. [2] We first verified the VO₂ stoichiometry through locally resolved XAS and analyzed the surface lattice in μ LEED at the SPELEEM installed at the CIRCE beamline of the ALBA Synchrotron in Barcelona. This was done on a Ru(0001) substrate where differently oriented RuO₂ islands were grown simultaneously as “virtual substrates”. LEED shows that VO₂ grows relaxed on RuO₂(100) but pseudomorphic on RuO₂(110), where it also features a previously not reported (2×2) reconstruction. [3] The reconstruction is attributed to the atomic-oxygen-induced oxygen termination of the film; we confirm this by reproducing VO₂(110)-(2×2) on TiO₂(110) substrates, also using atomic oxygen.

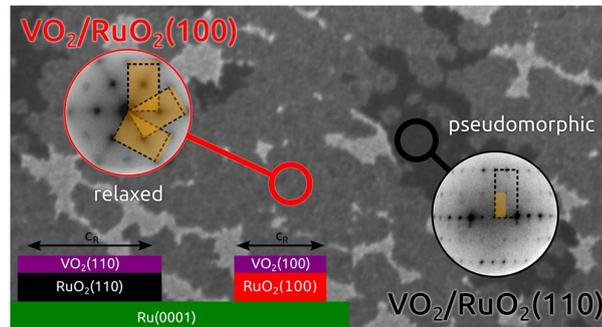


Figure 1. Two locally obtained LEED images of VO₂/RuO₂(100) (32.0 eV) and VO₂/RuO₂(110) (34.5 eV) showing relaxed and pseudomorphic growth, respectively. The background consists of a LEEM image (10.4 eV) of the same sample state. [3]

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References

- [1] C. Weber, D. D. O'Regan, N. D. M. Hine, M. C. Payne, G. Kotliar, P. B. Littlewood. *Phys. Rev. Lett.* **108**, 256402 (2012).
- [2] Y. Muraoka, Z. Hiroi. *Appl. Phys. Lett.* **80**, 583 (2002).
- [3] S. Fischer, J.-O. Krisponeit, M. Foerster, L. Aballe, J. Falta, J. I. Flege, *Cryst. Growth Des.* **20**, 2734 (2020).